History / Achievement

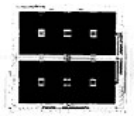
1976-1988

1976

· [Establishment of Large Scale Integrated Memory Division]
· Corroboration of Long Wave Length Band Optical

1977

· Fabrication of a 64 kbit Memory (DRAM)
· Fabrication of Optical Fiber by Vapor-phase Axial Deposition

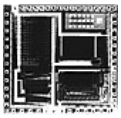


1978

· Invention of SIMOX Technology

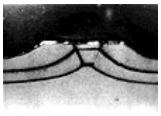
1979

· Development of a Single-chip LSI for PARCOR Speech Synthesis
· Fabrication of a 256 kbit Memory (DRAM)
· Development of 0.2 dB/km very low loss Optical Fiber



1980

· Development of Super-High-Purity Optical Fiber
· Invention of Master Key Method of Public Key Cryptosystem
· Sustained Room Temperature Operation of 1.55 μm Semiconductor Laser



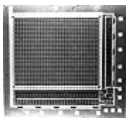
1981

· Fabrication of CMOS 32 Bit VLSI Processor* Sustained Room Temperature Operation of DFB Laser

1982

· [Establishment of Functional Device Research Department]
· Measurement of Soliton transmission on Joseffson transmission line

· Fabrication of 1 Mbit Memory (DRAM)



· Gallium Arsenide 1Kbit LSI Memory

1983

· [Establishment of Atsugi Electrical Communications Laboratories]

1984

· [Establishment of Information Communications and Materials science basic Research Department]
· Achievement of a dislocation-free 2inch Gallium Arsenide Crystal

1985

· [Privatization, the Birth of Nippon Telegraph and Telephone Corporation]
· [Establishment of Basic Research Laboratories]
· Invention of Migration Enhanced Epitaxy (MEE)

1986

· Development of High-Speed Fabrication of Single-mode Optical Fiber using the Full VAD Synthesis Process
· Invention of Phonocode Speech Encoding Method
· Development of Travelling Wave Semiconductor Optical Amplifier
· Invention of 1.5μm band Zero Dispersion Fiber
· Development of Planar Light Wave Circuit (PLC) Design and Fabrication Technology
· Development of DS Type Optical Connectors

1987

· [Establishment of LSI Laboratories, and Opto-electronics Laboratories]
· Development of Ballistic Carrier Transistor (BCT)
· Fabrication of 16 Mbit Level DRAM TEST Devices
· Fabrication of Oxide Superconductor Thin Films
· Generation of Amplitude Squeezed Light in Semiconductor Lasers
· Successful control of Neurite Growth Orientation
· Successful Emission of SOR Light

1988

· Development of High Speed LSI Probing Technology (EOS)
· Fabrication of Narrow Spectrum Line Width Multi-electrode DFB Laser
· Practical Use of SC Type Optical Connectors